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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

New York, New York

Katsuhiko MIYA et al.

Date: November 13, 2003

Serial No.: 10/648,918

Group Art Unit: Not Yet Assigned

Filed: August 27, 2003

Examiner: Not Yet Assigned

For: SUBSTRATE PROCESSING APPARATUS AND SUBSTRATE PROCESSING
METHOD DRYING SUBSTRATE

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

SUBMISSION

Sir:

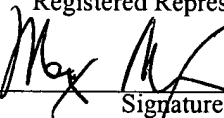
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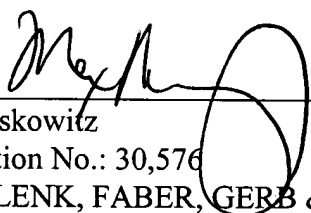
Respectfully submitted,

Max Moskowitz


Name of applicant, assignee or
Registered Representative


Signature

November 13, 2003
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Enclosures

		Application 10/648,918		OFGS File No. P/1250-258			
		Applicant Katsuhiko MIYA et al.					
		Filing Date August 27, 2003		Group Art Unit			
U.S. PATENT DOCUMENTS							
Examiner Initial	Document Number	Date MM-YYYY	Name	Class	Sub-class	Filing Date If Appropriate	
	US- 2002/0074020 A1	06/2002	Ono et al.			08/29/2001	
	US-						
	US-						
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FOREIGN PATENT DOCUMENTS							
	Document Number	Date MM-YYYY	Country	Class	Sub-class	Translation	
						Yes	No
	11-274135	10-1999	Japan				X
	2002-176026	06-2001	Japan			X	
	11-176795	07-1999	Japan				X
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)							
	English translation of Abstract for Japanese Patent Application Laid Open No. 11-274135						
	English translation of Abstract for Japanese Patent Laid Open No. 11-176795						
	Japanese Patent Application Laid Open No. 2002-176026 which is the counterpart						
	to U.S. Patent Application Publication No. 2002/0074020 A1 (as listed above)						
Examiner		Date Considered					
<small>EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.</small>							